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U.S. PATENT DOCUMENTS							
EXAMINER'S INITIALS	*PATENT NO.	*ISSUE DATE	*INVENTOR NAME	CLASS	SUBCLASS	FILING DATE	
U.S. PATENT APPLICATION PUBLICATIONS							
	*PATENT APPLN. PUB. NO.	*PUB. DATE	*APPLICANT	CLASS	SUBCLASS		
U.S. PATENT APPLICATIONS							
	*APPLN. NO.	*FILING DATE	*INVENTOR	CLASS	SUBCLASS		
FOREIGN PATENT DOCUMENTS							
EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						Yes	No
	JP 02-148645	06-1990	Japan (Japanese Full Text and English Abstract)			X	
	JP 09-265913	10-1997	Japan (Japanese Full Text and English Abstract)			X	
	JP 09-237580	09-1997	Japan (Japanese Full Text and English Abstract)			X	
	JP 03-190039	08-1991	Japan (Japanese Full Text and English Abstract)			X	
	JP 06-044907	02-1994	Japan (Japanese Full Text and English Abstract)			X	
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	JP 08-250029	09-1996	Japan (Japanese Full Text and English Abstract)			X	
	JP 11-288250	10-1999	Japan (Japanese Full Text and English Abstract)			X	
OTHER ART (Including Author, Title, Date, Pertinent Pages, Publisher, Place of Publication, Etc.)							
Japanese Office Action dated December 18, 2007.							
EXAMINER				DATE CONSIDERED			

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